

Fig. 1a

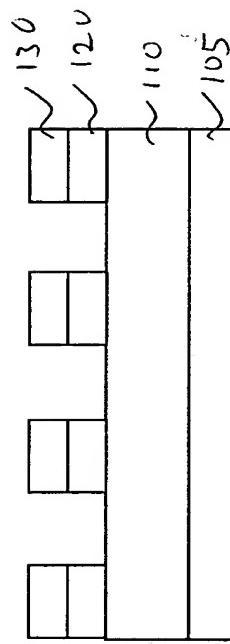


Fig. 1b

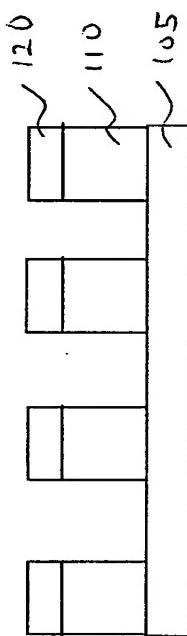
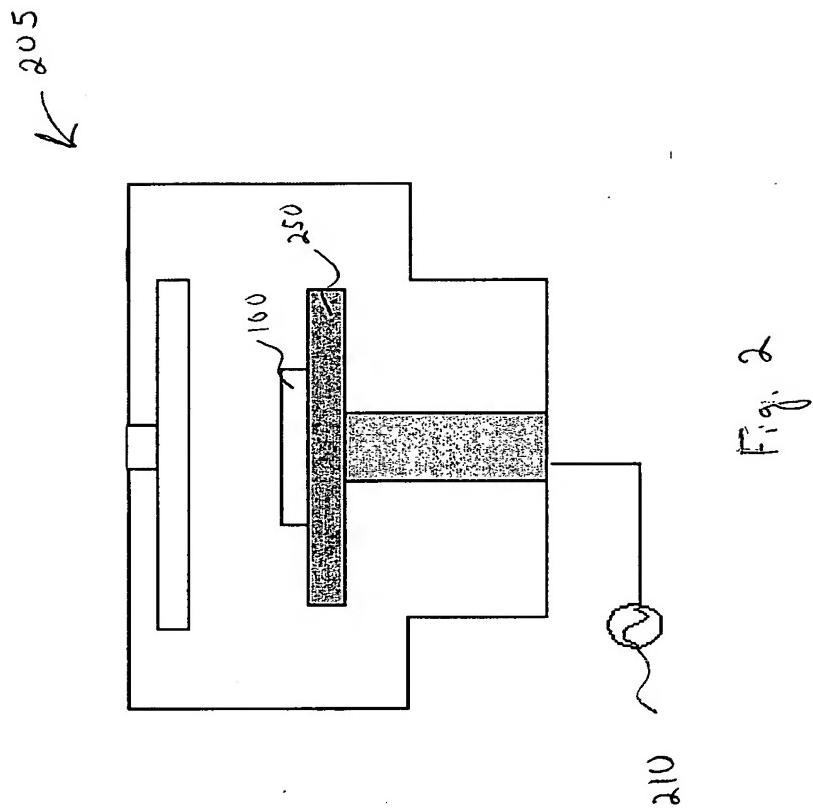


Fig. 1c



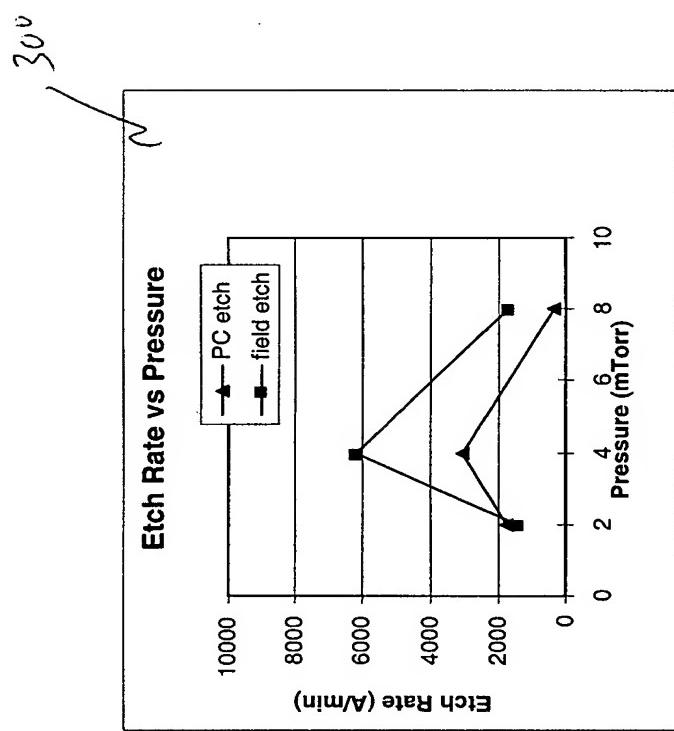
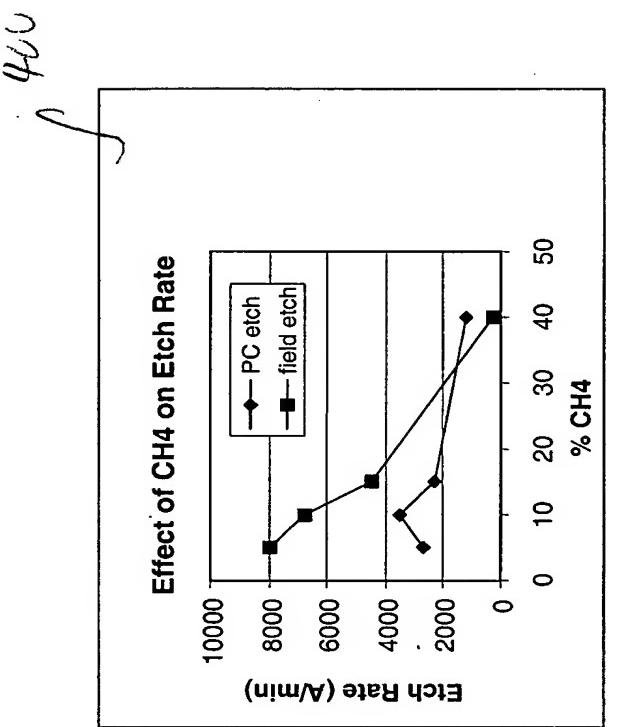


Fig. 3



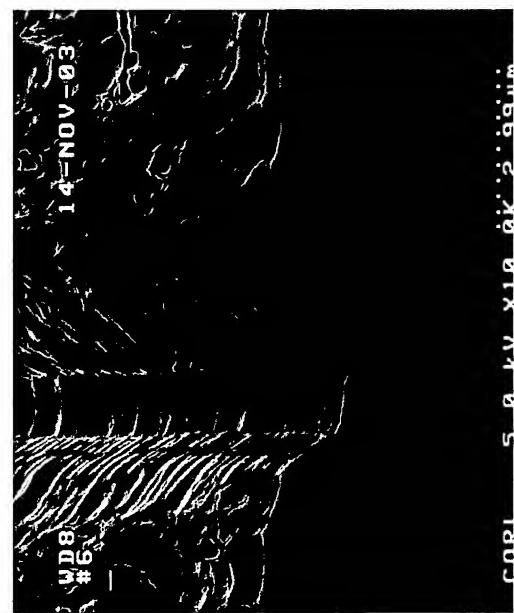


Fig. 5b



Fig. 5a

Title: Method for Etching High Aspect Ratio Features...

Inventors: Laura Wills Mirkarimi

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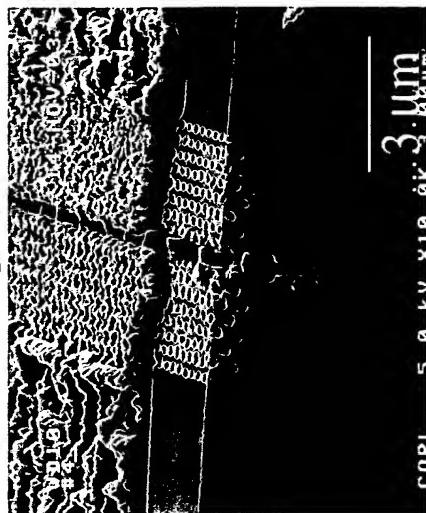


Fig. 6b

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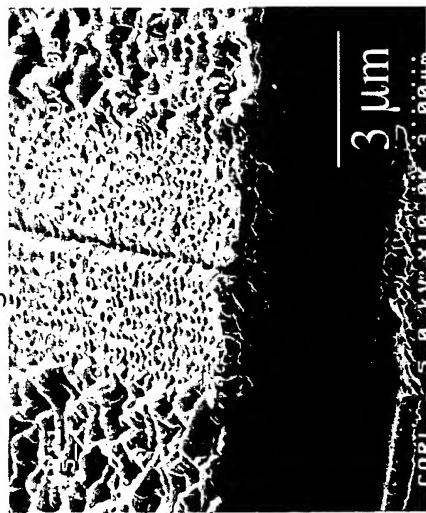


Fig. 6a